



Characterization of On-Chip Spiral Inductors

ECE 6450

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Why On-Chip Inductors?

- RF designs require many passive components in discrete form
- Reduce Cost & Area of RF integrated circuits
- Key element in amplifiers, mixers, and oscillators

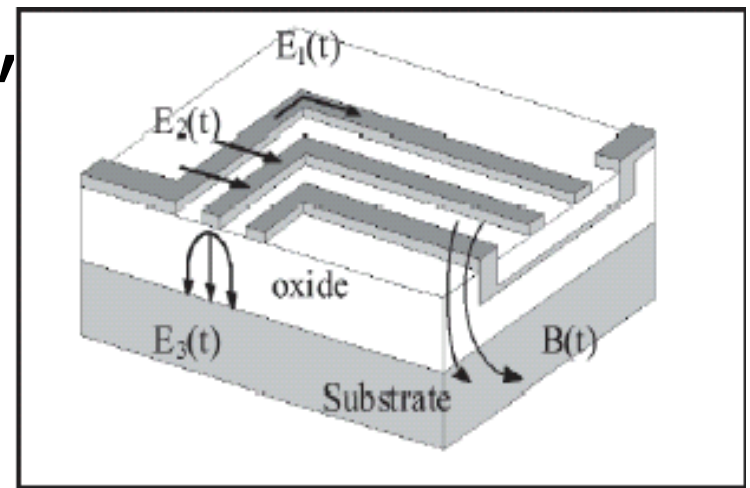
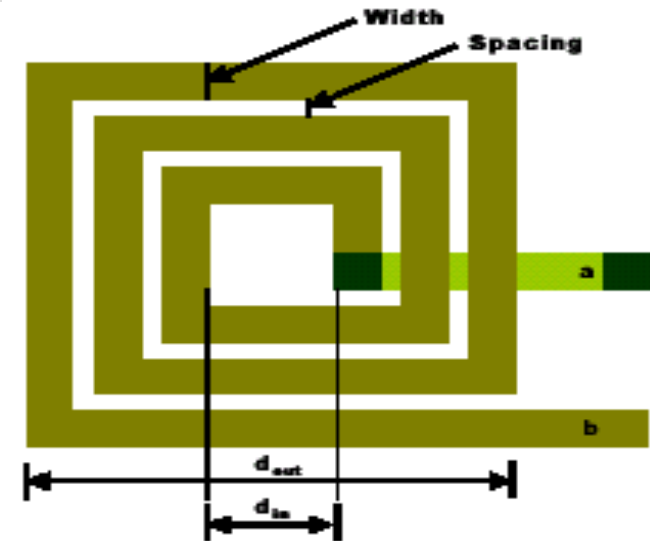


Key Inductor Parameters

- Quality Factor(Q)
- Inductance(L)
- Self-resonant frequency(F_{srf})

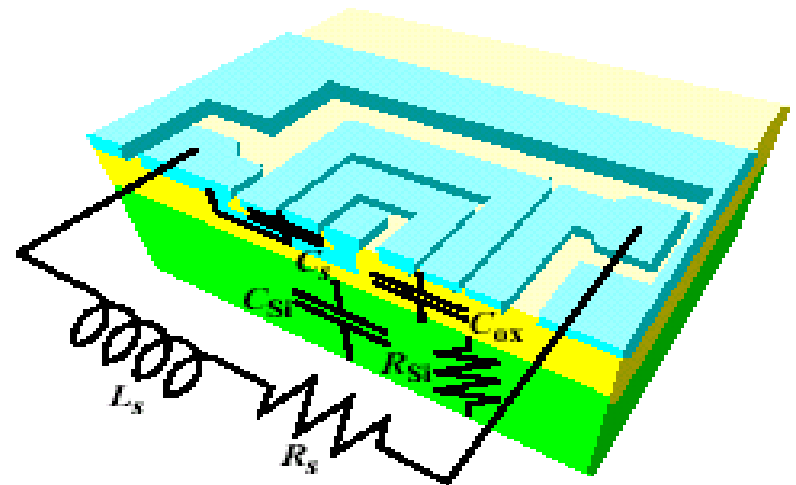
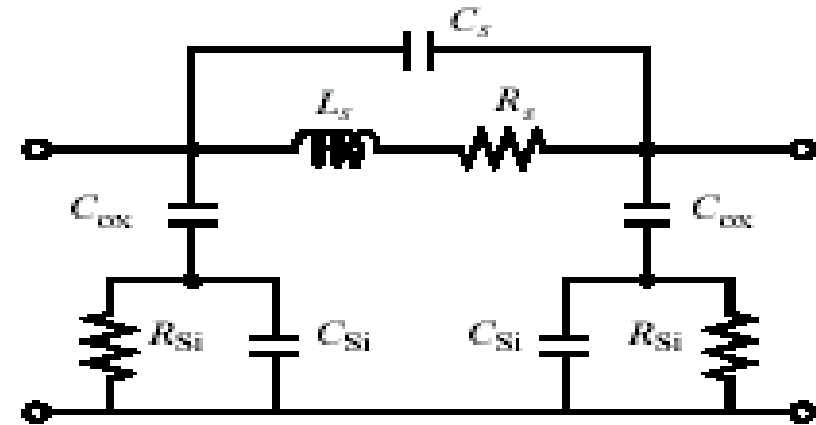
Inductor Geometry

- Square, circular, or octagonal structures are used
- Silicon technology is being investigated as an alternative to GaAs.
- Silicon substrate is cheaper, but has low resistivity
- 3D coils may also be used



Inductor Model

- Series inductance and resistance (L_s and R_s)
- Series Capacitance (C_s)
- Substrate parasitics (C_{ox} , C_{si} , and R_{si})





Series Inductance(L_s)

- Comprised of self(L_{self}) and mutual(M) inductances.

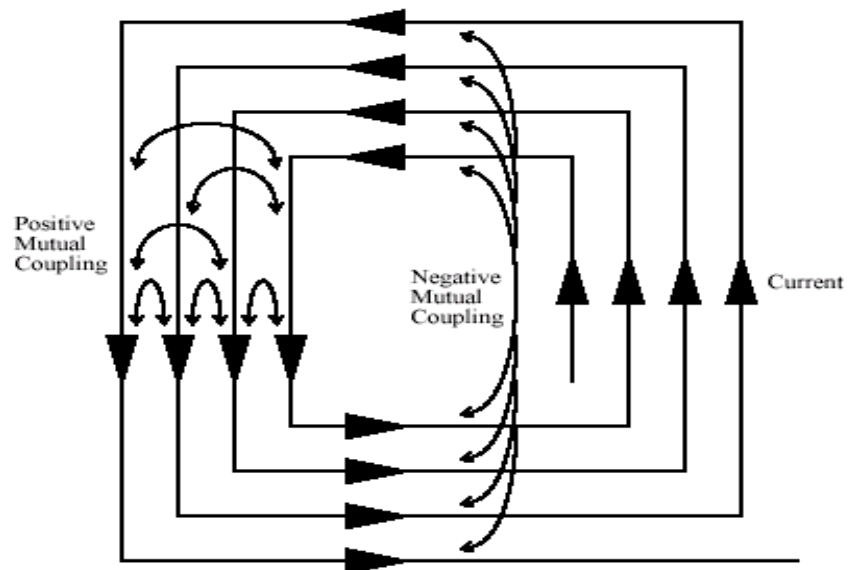
$$L_{\text{self}} = 2l[\ln(2l/(w+t)) + 0.5 + (w+t)/3l]$$

l = wire length; w = width; t = thickness

$$M = k * \text{SQRT}(L_1 L_2) = kL$$

Series Inductance(L_s)

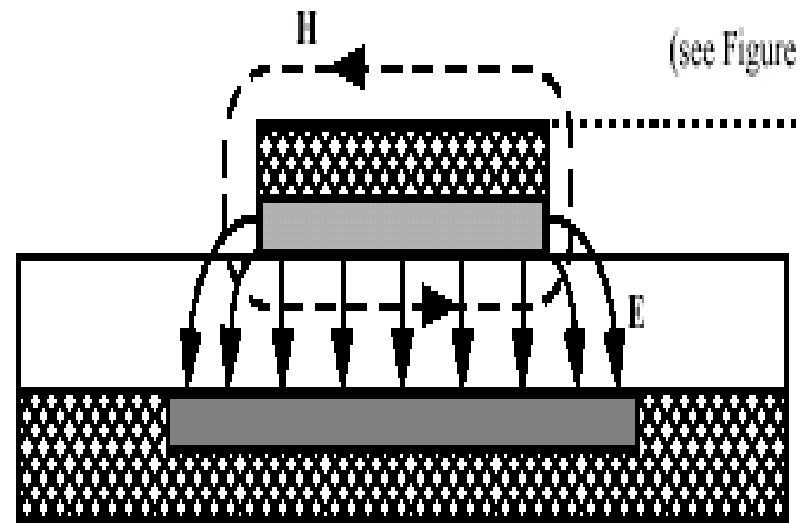
- Greenhouse Method – L_{total} can be computed by summing L_{self} of each wire segment and the positive and negative mutual inductance between all possible wire segment pairs.



Series Resistance(R_s)

- Eddy currents reduce the net current flow in the inductor and hence increase the resistance

$$R(f) = V / (J(f) * A)$$





Series Resistance(R_s)

$$R = \rho * l / (w * t_{\text{eff}})$$

ρ = resistivity of wire

l = length of wire

w = width of wire

t_{eff} = effective thickness of wire

Series Capacitance(Cs)

- Models the parasitic capacitive coupling between input and output ports
- Sum of all overlap capacitances of the spiral and the underpass

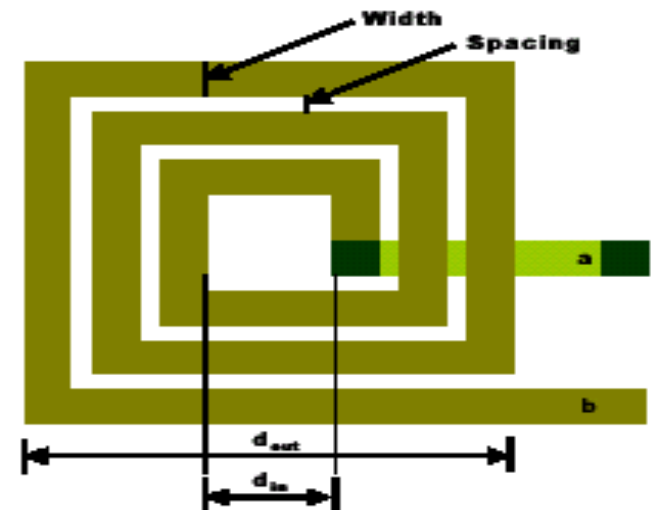
$$C_s = n \cdot w^2 \cdot \frac{\epsilon_{ox}}{t_{oxM1-M2}}$$

N=# of overlap

w= spiral line width

$t_{oxM1-M2}$ =oxide thickness

btwn spiral & underpass





Substrate Parasitics(C_{ox} , C_{si} , R_{si})

C_{ox} = oxide capacitance

C_{si} and R_{si} represent the substrate capacitance and resistance respectively.

Assumed to be distributed equally at both ends of the inductor.

C_{si} and R_{si} are proportional to the area occupied by the inductor.



Substrate Parasitics(C_{ox} , C_{si} , R_{si})

$$C_{ox} = 0.5 * L * w * e_{ox} / t_{ox}$$

$$C_{ox} = 0.5 * L * w * C_{sub}$$

$$R_{si} = 2 / (L * w * G_{sub})$$

e_{ox} = dielectric constant

L = spiral length

t_{ox} = oxide thickness

w = width

C_{sub} and G_{sub} are capacitance and conductance per unit area for the substrates, and they are functions of the substrate doping.



Quality Factor(Q)

- Measure of how 'pure' an inductor is.
 - Impedance(Z) of inductor = $R + jX$
 - High Q is critical
 - higher the Q, the fewer the losses
- $$Q = X/R$$



Conclusion

- Ways to improve Q ?
 - place inductor far from substrate
 - use metal with low resistance
 - ground shield
 - MEMS technology